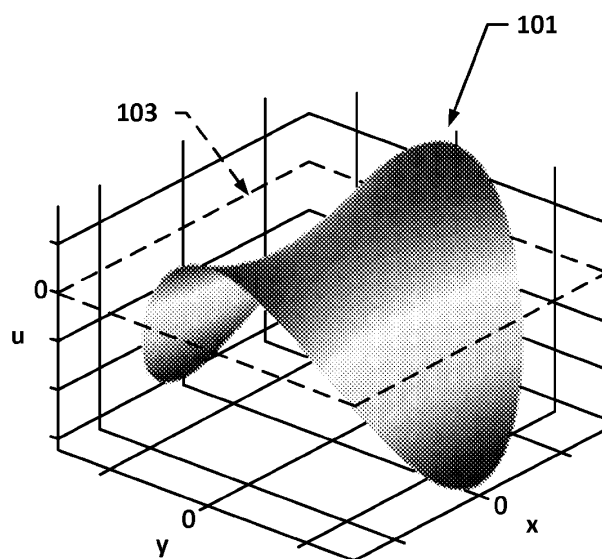


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**FIG. 1**

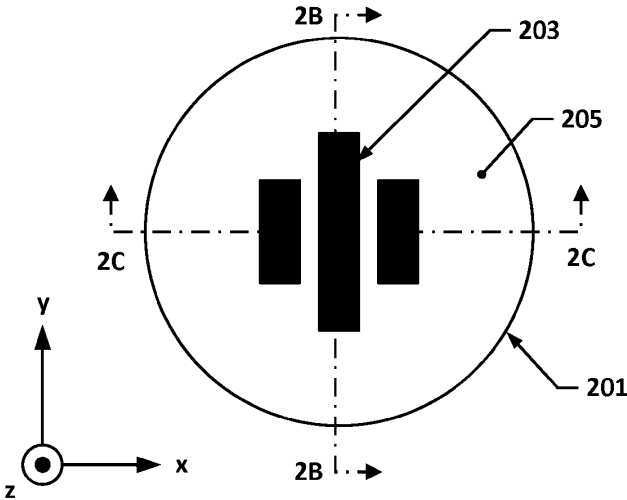


FIG. 2A

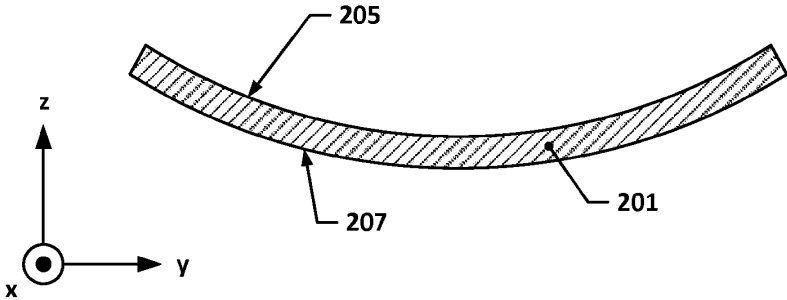


FIG. 2B

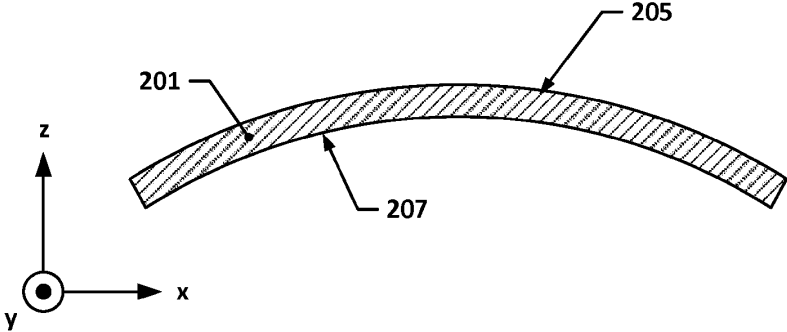
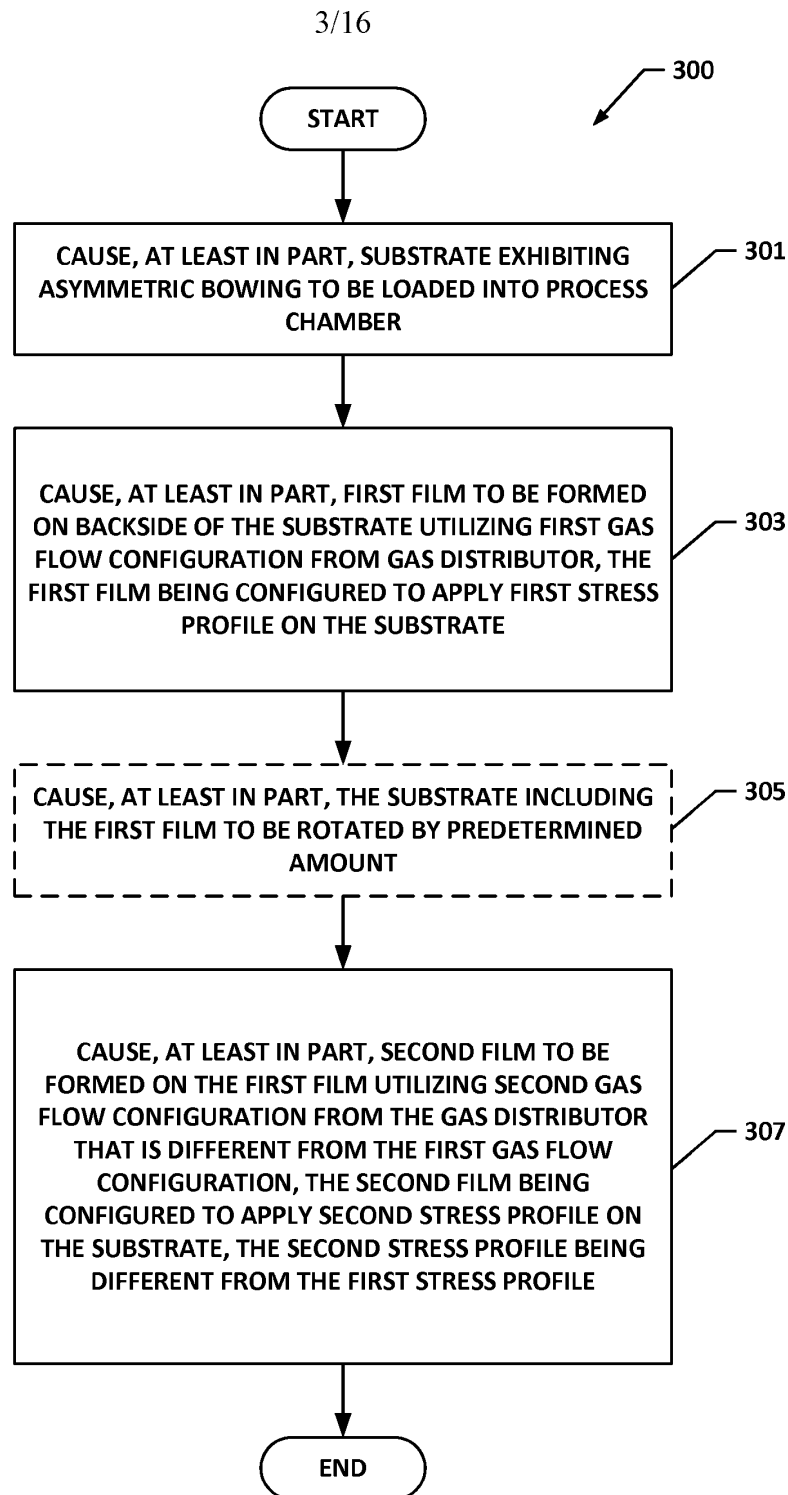


FIG. 2C

**FIG. 3**

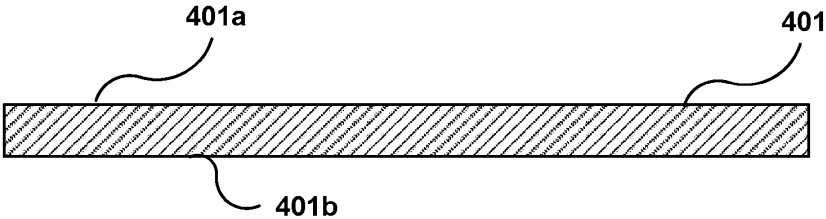


FIG. 4A

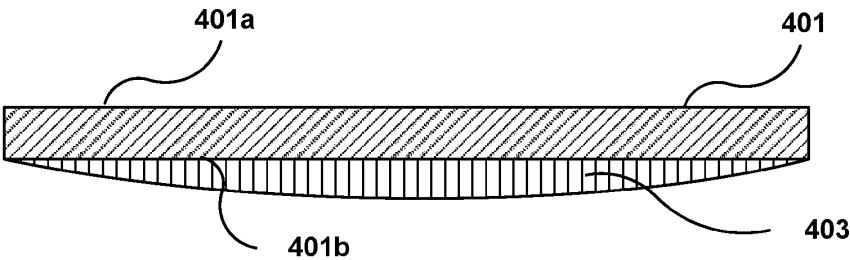


FIG. 4B

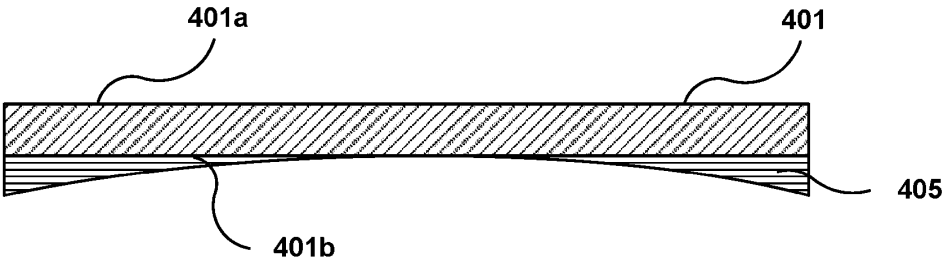


FIG. 4C

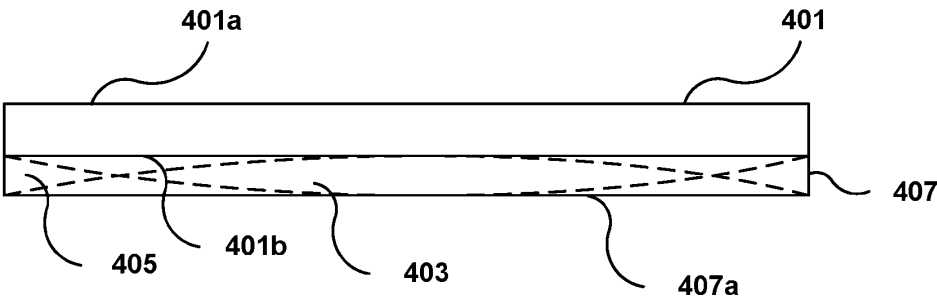


FIG. 4D

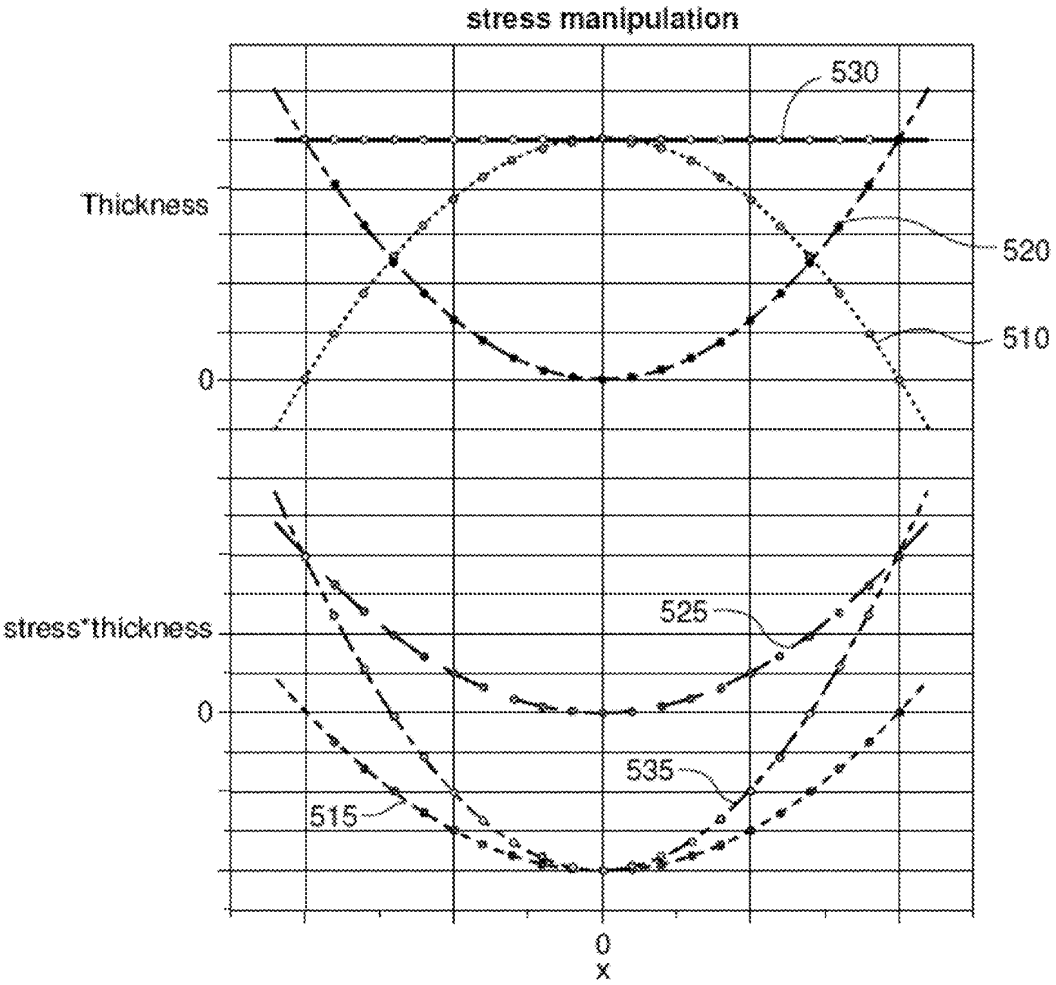
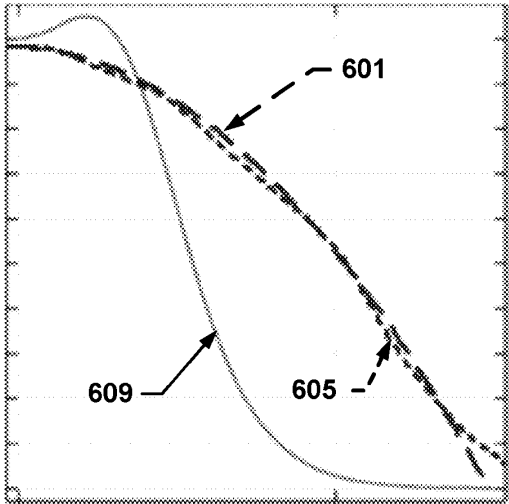


FIG. 5

DEPOSITION PROFILE

FIRST GAS
(E.G., REACTANT GAS)
CONCENTRATION

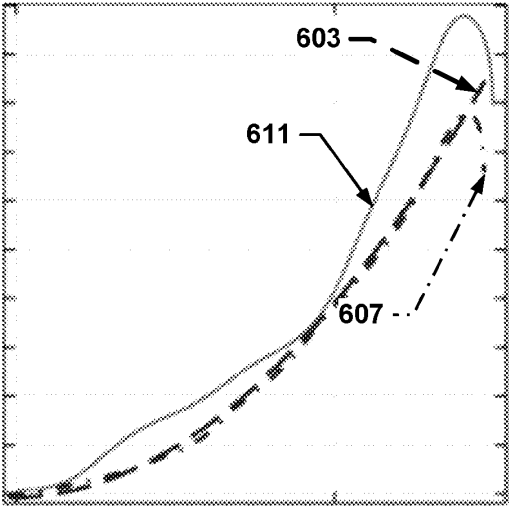


WAFER RADIUS

FIG. 6A

DEPOSITION PROFILE

SECOND GAS
(E.G., DILUTION GAS)
CONCENTRATION



WAFER RADIUS

FIG. 6B

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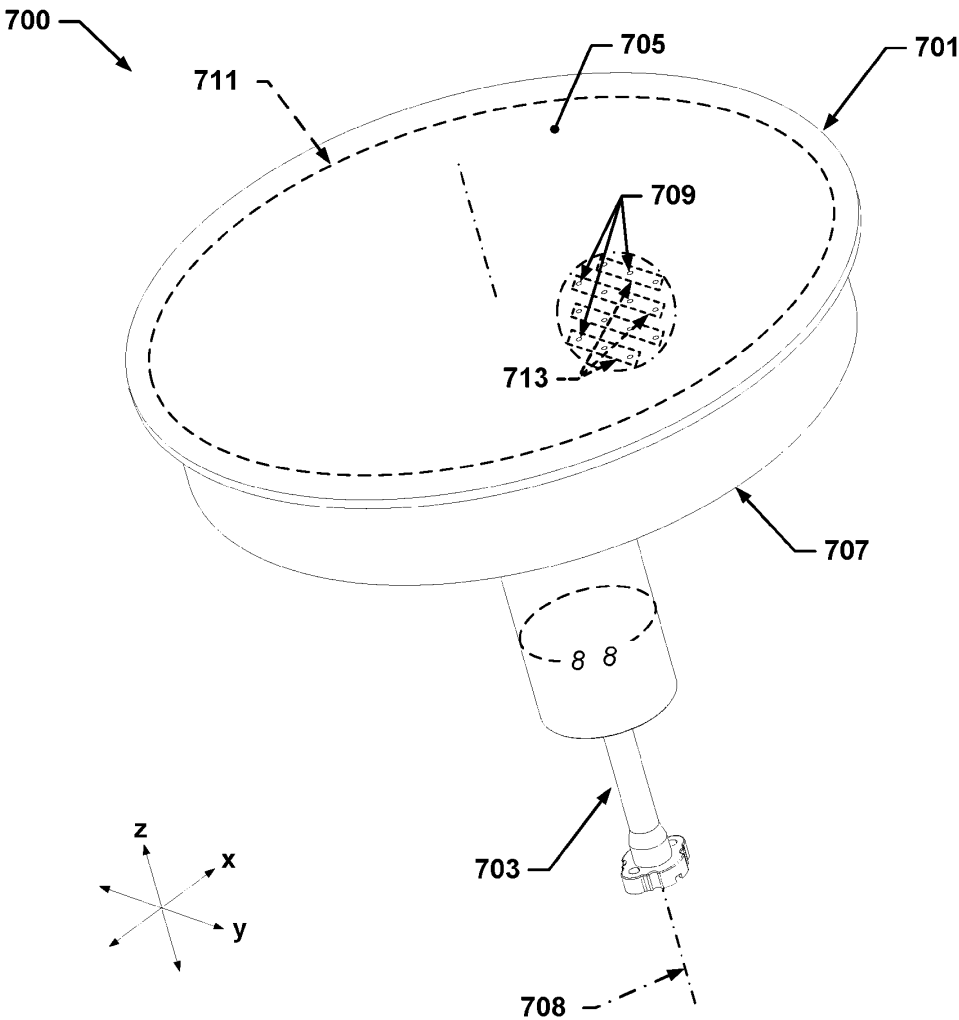


FIG. 7

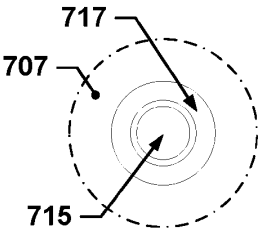


FIG. 8

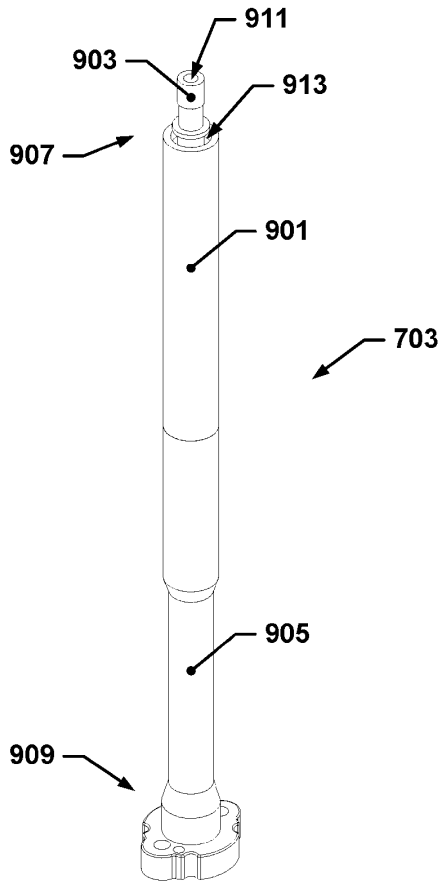


FIG. 9

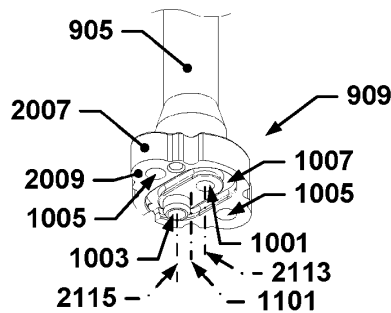


FIG. 10

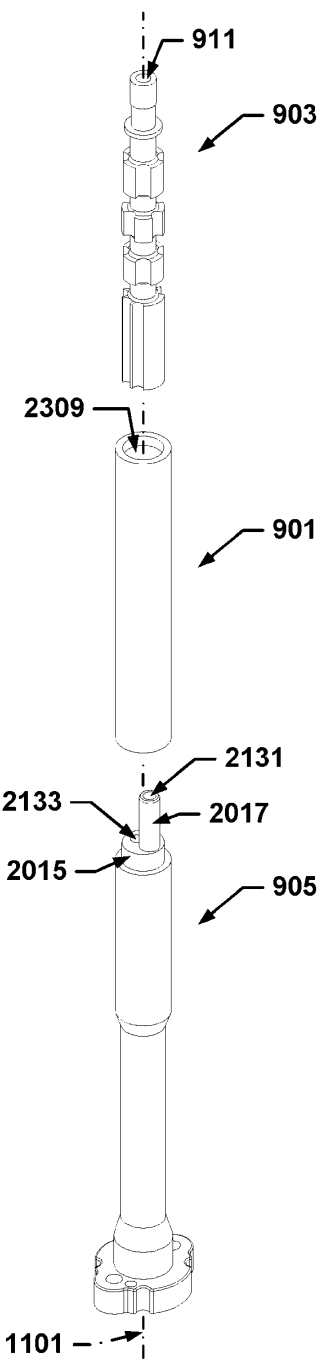


FIG. 11

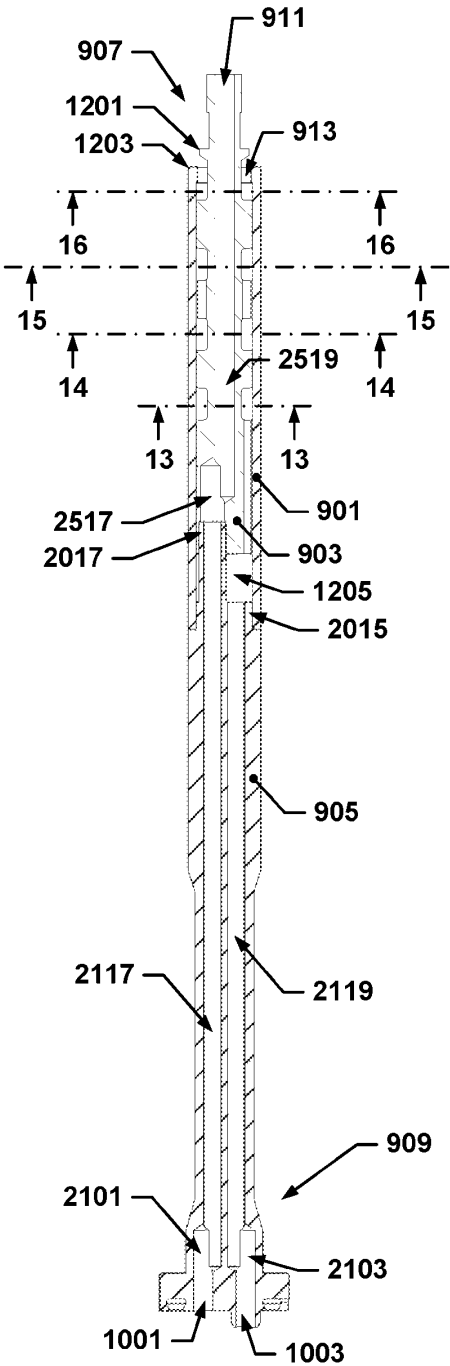


FIG. 12

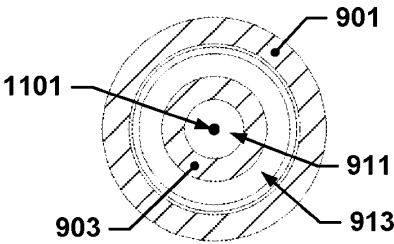


FIG. 16

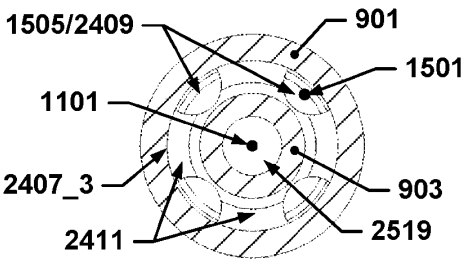


FIG. 15

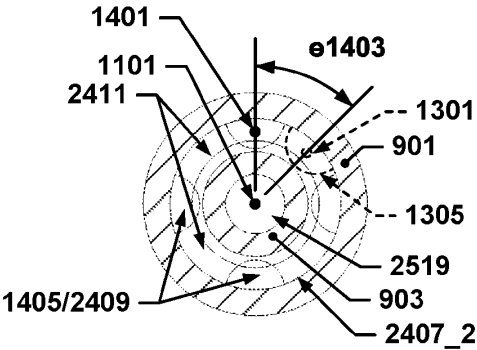


FIG. 14

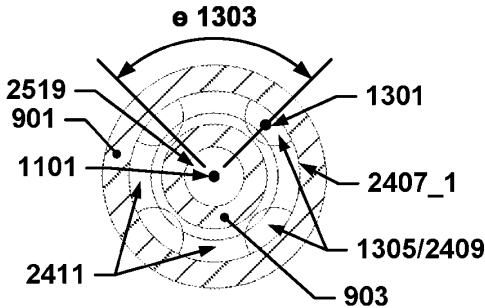


FIG. 13

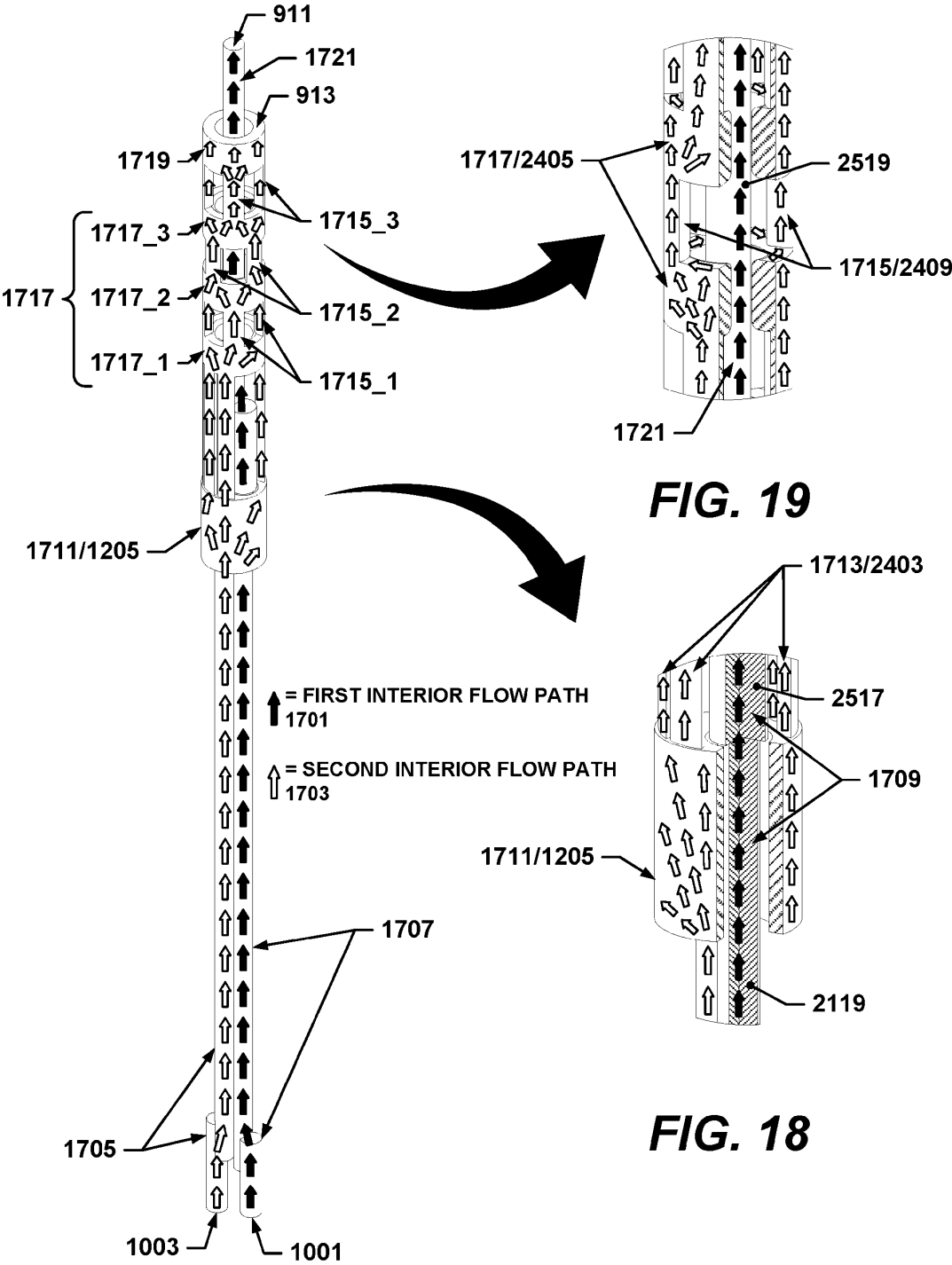


FIG. 17

FIG. 19

FIG. 18

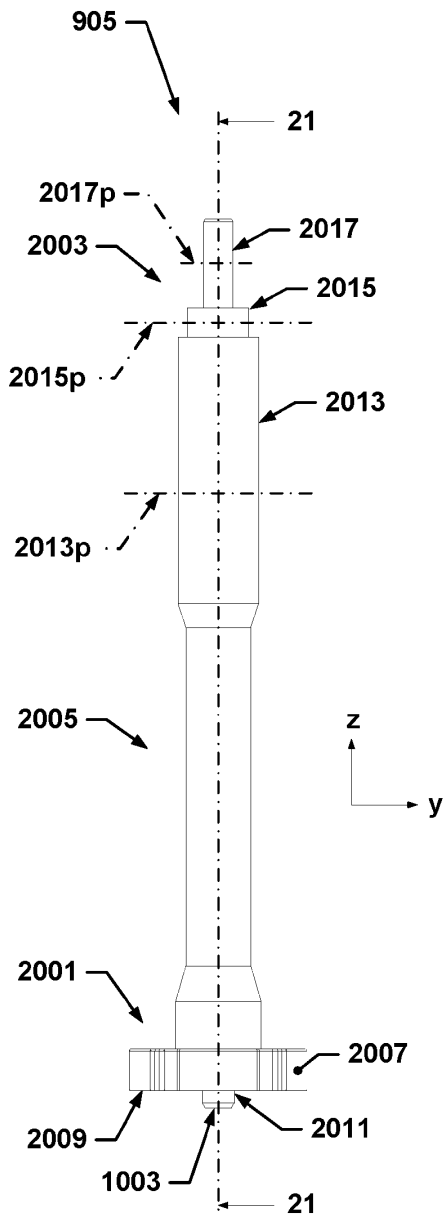


FIG. 20

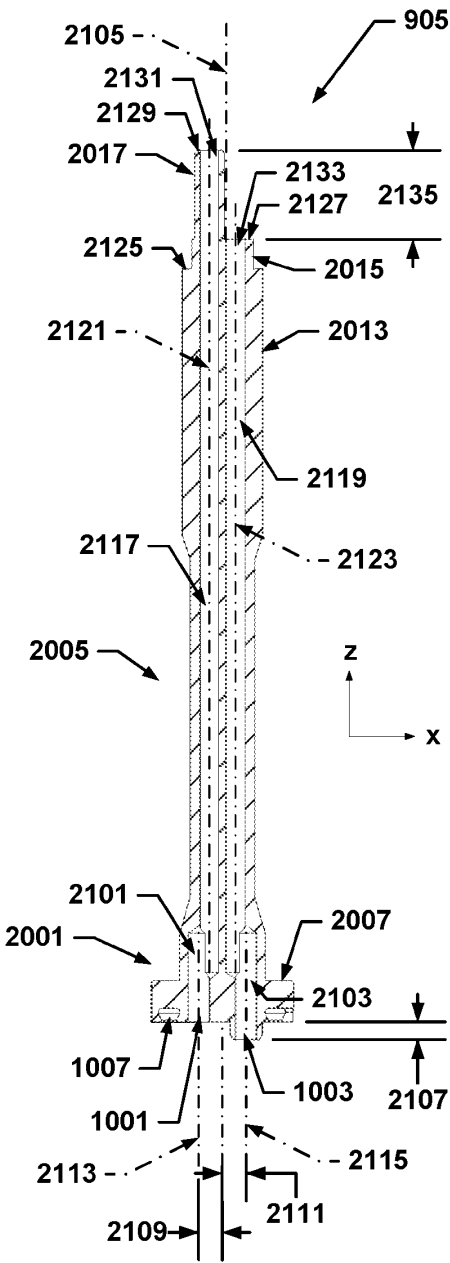


FIG. 21

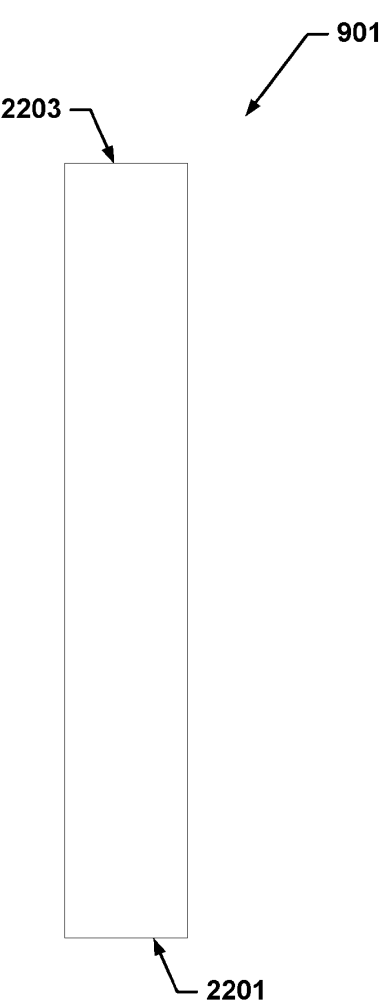


FIG. 22

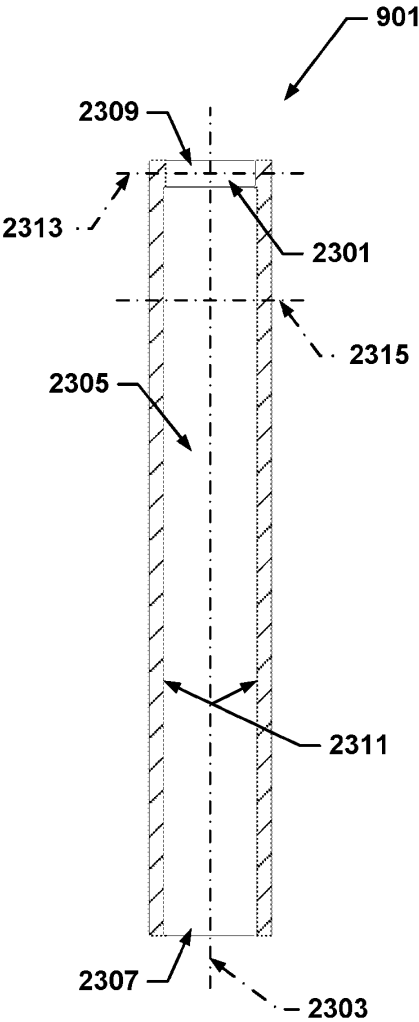


FIG. 23

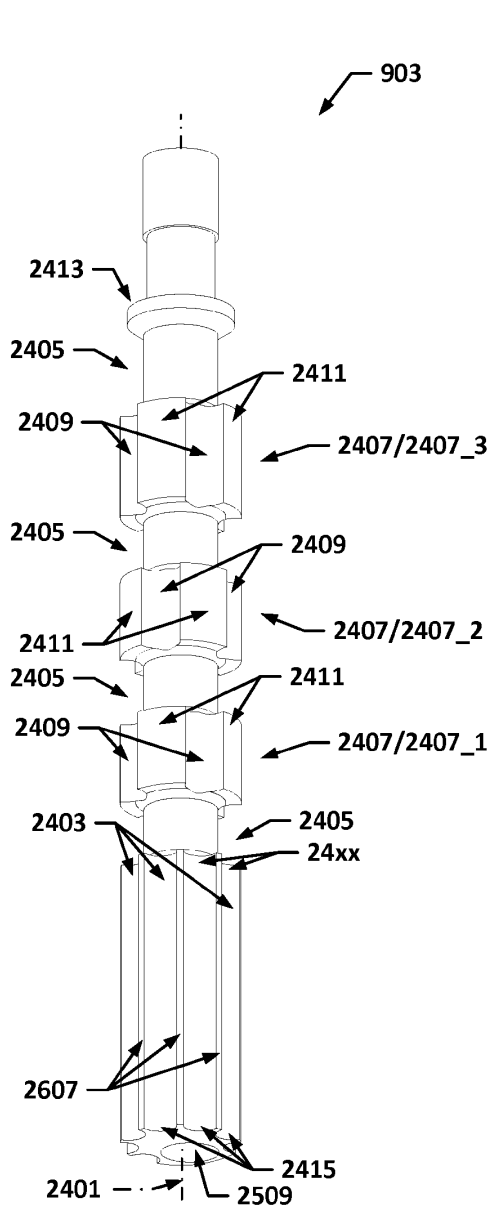


FIG. 24

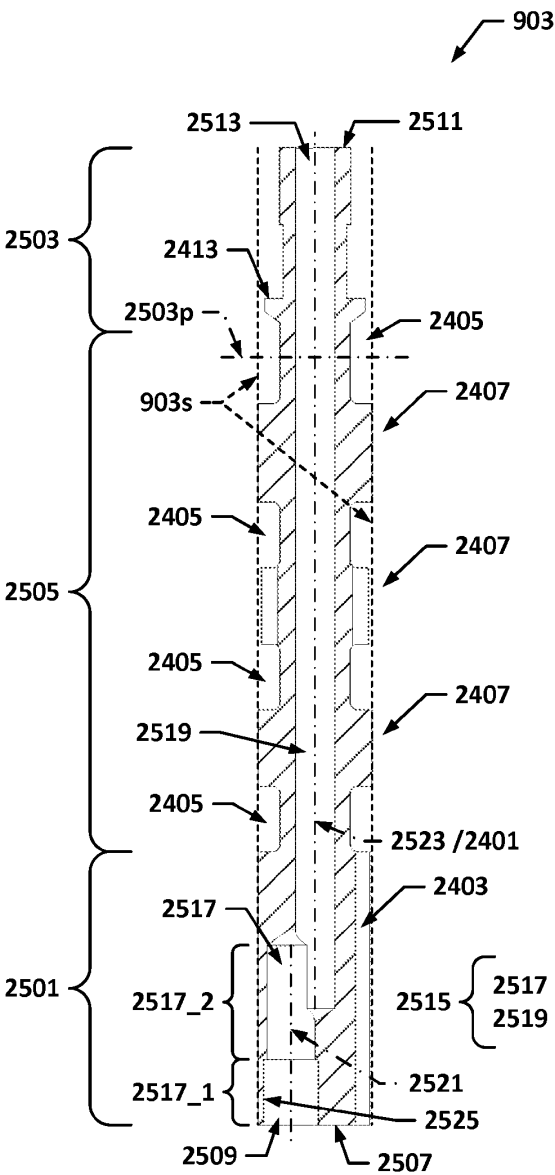


FIG. 25

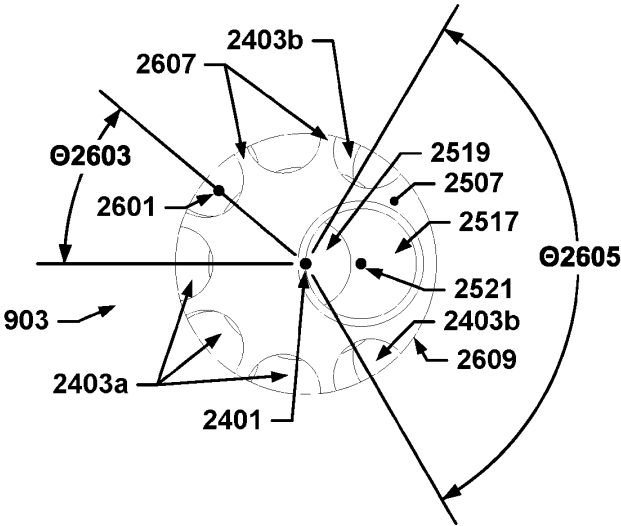
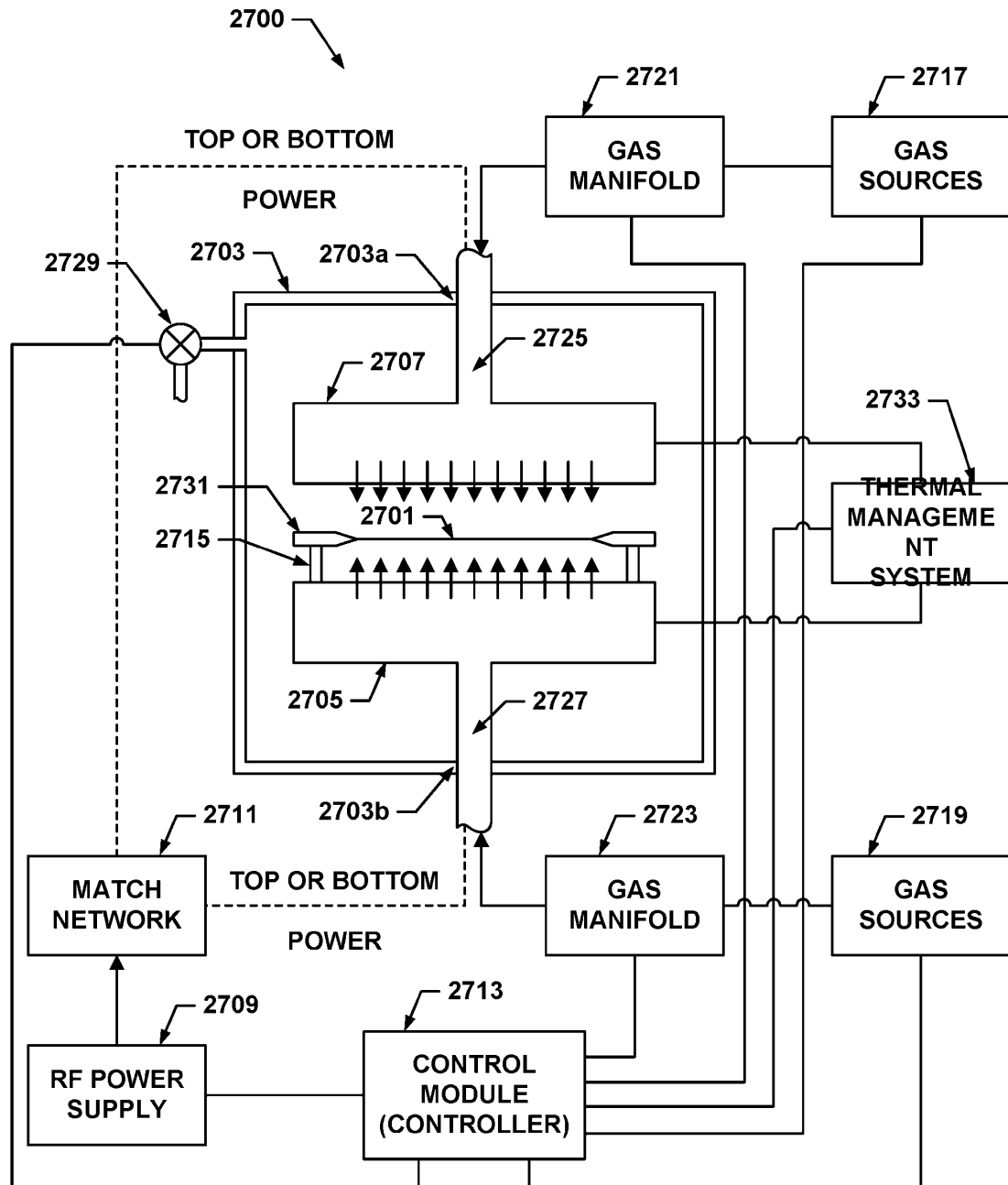


FIG. 26

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**FIG. 27**

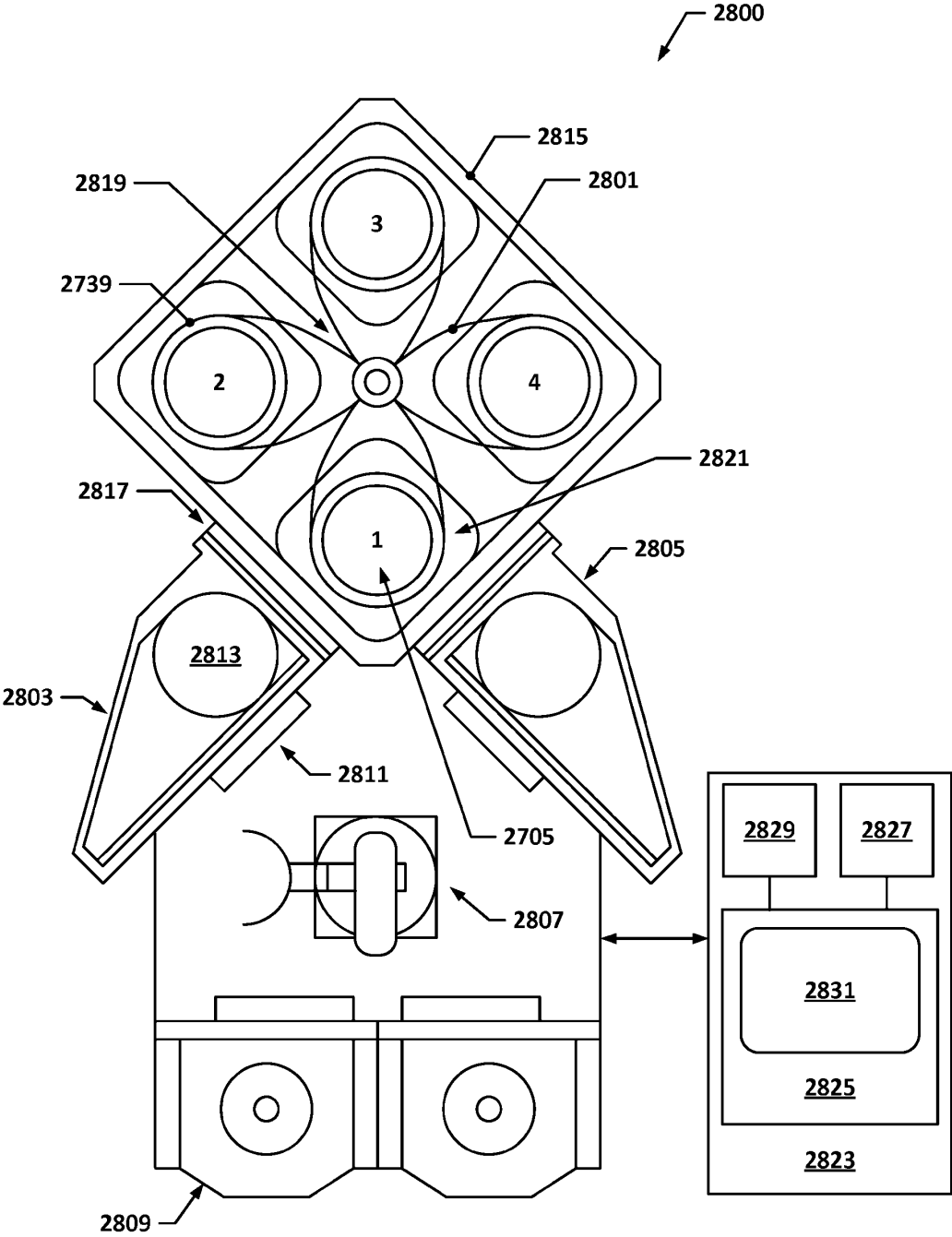


FIG. 28